


INFORMATION DISCLOSURE CITATION IN AN APPLICATION		Attorney Docket No. 13DV-13711	Application No. 10/063,808
Submitted by: 		Applicant: Ramgopal Darolia, et al	
Domenica N.S. Hartman, Reg. No. 32,701		Filing Date: 05/15/03	Group Art No. 1753

U.S. PATENT DOCUMENTS


Examiner's Initials	Document Number	Date	Name	Class	Subclass	Filing Date if appropriate
SHV	4,403,002	09/06/83	Akashi, et al	427	255.5	
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FOREIGN PATENT DOCUMENTS

Examiner's Initials	Document Number	Date	Country	Class	Subclass	Translation Yes No
	JP05156438	06/22/93	Japan	C23C	14/54	
	JP06322521	11/22/94	Japan	C23C	14/06	
SHV	EP1008669	06/14/00	Europe	C23C	14/30	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)


Examiner	
Date Considered	March 15, 2004

*Examiner: Initial if reference considered whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.



Electronic Information Disclosure Statement

PHYSICAL VAPOR DEPOSITION APPARATUS AND PROCESS

Application: 
10/063808
Confirmation: 4319
Applicant(s): Ramgopal Darolia
Docket Number: 13DV-13711
Group Art Unit: 1762
Examiner:
search string: (6007880).pn.


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US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Citation No.	Patent Number	Date	Bar Code	Patentee	Class	Subclass
SM	P01	6007880	1999-12-28		Maloney	427	585

Signature

Examiner Name	Date
	March 15, 2004